

Specifications

General

Principle:

Laser Light Scattering.

Analysis:

Mie and Fraunhofer scattering including a patented multiple scattering analysis.

Data acquisition rate:

Rapid mode: 10kHz. Continuous mode: 1Hz.

Maximum Measurement Time:

Rapid mode: 30 seconds. Continuous mode: 60 minutes.

Measurement Triggering:

Internal: Based on transmission or light scattering levels. External: Based on TTL input or simple switch trigger.

External Device Synchronization:

Via 2 TTL trigger outputs.

Optics

Light source:

Max 4mW He-Ne Laser, 632.8nm.

Lens arrangement:

Fourier (parallel beam).

Lens Focal Length:

300mm and 750mm.

Measurement range:

150mm at 0.5 μm , extending to greater than 1m above 5 μm .

Detector

Arrangement:

36 element log-spaced array.

Angular range:

0.015 – 17 degrees.**

Alignment:

Automatic.

Sizing Performance

Particle size:

300mm lens: 0.1 – 900 μm (Dv50: 0.5 – 600 μm). 750mm lens: 2 – 2000 μm (Dv50: 5 – 1600 μm).

Accuracy:

Better than 1%.***

Repeatability:

Better than 1%.***

Reproducibility:

Better than 1%.***

Software

21 CFR part 11:

Enables an operating mode that assists with ER/ES compliance.

System Compliance

Laser safety:

Class 3R, IEC60825-1:2007 and CFR Chapter 1: Sub-chapter J: Part 1040 (CDRH).

Regulatory testing:

CE / FCC compliant. Meets requirements of the European Low Voltage directive.

Weight and dimensions

Laboratory systems:

950mm optical bench: 950mmx550mmx610mm (36kg). 1400mm optical bench: 1400x550x610 (37kg).

Spray Facility Systems:

950mm optical bench: 950mmx550mmx650mm (36kg). 1400mm optical bench: 1400x550x650 (37kg).

System

Power:

100/240 v, 50/60 Hz.

Product storage temperature:

-20°C to +50°C.

Operating temperature (°C):

+15°C to +40°C.

Humidity:

80% maximum for temperatures up to 31°C, decreasing linearly to 50% at 40 °C. Non-condensing.

Ingress Protection (IP) rating:

IP65 when in normal use

Notes

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This defines the maximum allowable distance between the far edge of the spray plume and the Spraytec receiver lens.

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Lens dependent.

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Relates to the measurement of the Dv50 for NIST-traceable latex standards. Sample dependent.